

L Number	Hits	Search Text	DB	Time stamp
1	852	kobayashi-shinji\$.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 13:51
2	170	kitano-takahiro\$.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 13:51
3	147	sugimoto-shinichi\$.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 13:52
4	6717	(semiconductor or wafer or substrate or disk or disc) near13 (solvent near3 evaporat\$)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 13:53
5	1068824	vacuum or (reduced adj pressure) or (negative adj pressure)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 13:54
6	1151060	vacuum or (reduced adj pressure) or (negative adj pressure) or evacuat\$	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 13:59
7	2984	(vacuum or (reduced adj pressure) or (negative adj pressure) or evacuat\$) and ((semiconductor or wafer or substrate or disk or disc) near13 (solvent near3 evaporat\$))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 14:13
8	439	((vacuum or (reduced adj pressure) or (negative adj pressure) or evacuat\$) and ((semiconductor or wafer or substrate or disk or disc) near13 (solvent near3 evaporat\$))) and (solvent near3 reduc\$)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 14:16
9	1	((vacuum or (reduced adj pressure) or (negative adj pressure) or evacuat\$) and ((semiconductor or wafer or substrate or disk or disc) near13 (solvent near3 evaporat\$))) and (solvent near3 reduc\$) and (straighten\$ near3 vane)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 14:02
10	23032	(clamp or clamping) near3 (semiconductor or wafer or substrate or disk or disc)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 14:03
11	4	((vacuum or (reduced adj pressure) or (negative adj pressure) or evacuat\$) and ((semiconductor or wafer or substrate or disk or disc) near13 (solvent near3 evaporat\$))) and (solvent near3 reduc\$) and ((clamp or clamping) near3 (semiconductor or wafer or substrate or disk or disc))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 14:05
12	7	("4633804" "5059266" "5578127" "5662785" "5804046" "6033480" "6063190").PN.	USPAT	2004/09/02 14:04
13	67	((vacuum or (reduced adj pressure) or (negative adj pressure) or evacuat\$) and ((semiconductor or wafer or substrate or disk or disc) near13 (solvent near3 evaporat\$))) and (solvent near3 reduc\$) and (aligner or alignment or aligning)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 14:18

14	208080	control?\$4 near3 (pressure or vacuum\$ or evacuat?\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 14:14
15	1390	(control?\$4 near3 (pressure or vacuum\$ or evacuat?\$3)) and (solvent near3 reduc\$)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 14:17
16	4411	(control?\$4 near3 (pressure or vacuum\$ or evacuat?\$3)) and (solvent near3 remov?\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 14:17
18	648	((control?\$4 near3 (pressure or vacuum\$ or evacuat?\$3)) and (solvent near3 remov?\$3)) and (aligner or alignment or aligning)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 14:18
17	116	((control?\$4 near3 (pressure or vacuum\$ or evacuat?\$3)) and (solvent near3 reduc\$)) and (aligner or alignment or aligning)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/02 14:18